

U.S. UTILITY PATENT APPLICATION

FA 500 (10)

APPLICATION NO. 09/811447	CONT/PRIOR F	CLASS 355	SUBCLASS 30	ART UNIT 2851	EXAMINER Matthew A. [Signature]
APPLICANTS Shuichi Yabu					
TITLE Exposure apparatus, gas replacing method, and method of manufacturing a semiconductor device					
PTO-2010 12/23					

<p>CLASSICAL</p> <p>CLASSICAL</p>	<p>DRAWINGS</p> <p>20 25 1</p>		<p>CLAIMS ALLOWED</p> <p>100% CLAIMS</p> <p>8/52</p>
<p>The name of the patent</p> <p>(Date)</p>	<p>(Amount Due)</p> <p>(Date)</p>		<p>NOTICE OF ALLOWANCE MAILED</p> <p>6/28/03</p>
<p>The term of this patent shall</p> <p>not extend beyond the expiration date</p> <p>of U.S. Patent No.</p>	<p>Mr. A. [Signature]</p> <p>Primary Examiner</p> <p>6-28-03</p>		<p>ISSUE FEE</p> <p>Amount Due</p> <p>\$1600.00</p>
<p>The [Signature] [Signature]</p> <p>has been [Signature]</p>	<p>(Local Instruments Examiner)</p> <p>(Date)</p>		<p>ISSUE BATCH NUMBER</p>

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